

Full Associate Professor at Center for Low-temperature Plasma Science (cLPS),
Nagoya University

1. Number of Positions: One associate professor
2. Affiliation: Center for Low-temperature Plasma Sciences, Nagoya University.
The professor will also be in charge of education at the Department of Electrical Engineering, Electronics, and Information Engineering, School of Engineering, as well as Department of Electronics, Graduate School of Engineering
3. Research Field: Plasma Nano-process
4. Qualifications: Holder of a Ph. D degree, Excellent ability of research in the field of Plasma Nano-process, Ability to manage the cLPS, Teaching undergraduate- and graduate-level students.
5. Subject of Teaching: Electronic Engineering (especially Plasma Nano-process and related subjects).
6. Salary and benefits
 - Salary, working hours, and benefits are determined in accordance with the provisions of the Tokai National Higher Education and Research System Employee Work Rules.
https://education.joureikun.jp/thers_ac/act/frame/frame110010928.htm (Japanese only)
 - Salary is determined based on the annual salary system at Nagoya University.
https://education.joureikun.jp/thers_ac/act/frame/frame110001585.htm (Japanese only)
7. Expected Starting Date: Earliest possible date after April 1, 2024
8. Application Documents: Send a set of the following items by mail to the address below with a note
 - (1) Curriculum vitae with face photograph
 - (2) List of publications
 - (3) Reprints of five representative publications
 - (4) Summary of research achievements (about two pages)
 - (5) Research plan and essay on applicant's policy on education (about two pages)
 - (6) Management Policy and Future Vision for cLPS (about one page)
 - (7) Name, affiliation, and e-mail address of two contact references
 - (8) Other items the applicant considers useful for selection (number of citations, h-index, awards, grants, education experiences, social activities, etc.)# Submit a USB memory stick containing the files in PDF format and one printout of each.
9. Deadline: December 1, 2023(Deadline for receipt)
10. Selection Process: After document screening, we will have an individual interview. The selection result will be informed when a final candidate is decided.
11. Mailing Address: Prof. Noriyasu Ohno,
Center for Low-temperature Plasma Sciences, Nagoya University
Furo-cho, Chikusa-ku, Nagoya 464-8603, Japan
- ※N.B. Send the letter in registered mail. Write "Application form for Associate Professor Position at cLPS" in red on the envelope. Both application form and USB memory stick will not be returned to you.
12. Contact: Prof. Noriyasu Ohno,
E-mail: ohno (at) ees.nagoya-u.ac.jp
13. Remarks:
 - Additional materials may be requested during the selection process.

- Please note that application documents (including USB memory stick) will not be returned.
- Personal information contained in the submitted documents will not be used for any purpose other than selection and employment.
- The University actively promotes gender equality.
- This is international recruitment.
- Transportation expenses for interviews will not be provided.
- In November 2021, with the clarification of the scope of control of "deemed exports" under the Foreign Exchange and Foreign Trade Act ("FEFTA"), a portion of the provision of confidential information must comply with FEFTA. Technology provided by universities and research institutions to faculty and staff is FEFTA is subject to control. As a result of this change, faculty applications will also be subject to FEFTA controls. In accordance with this change, you will be required to submit an Applicable Specific Category Determination Form according to the Applicable Specific Category Determination Flowchart. Eligible applicants will be notified in advance. In addition, faculty members are required to submit a "Confirmation Form" at the time of employment.